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**Development of**  
**an Optical Coherence Tomography system**  
**and its application in surface morphology imaging**  
**of an optical material**

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A thesis submitted in fulfilment of the requirements  
for the degree of Master of Philosophy in Lasers and Applied Optics



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A Spectral-Domain Optical Coherence Tomography (OCT) system was developed by illuminating a Michelson interferometer with a broadband light-emitting diode. The system was developed for the purpose of surface profilometry of an optical material using the first reflection surface profilometry technique. Analytic solutions of the interference signal of a single wavelength, two-wavelength, polychromatic line and broadband sources were derived using the electric field solution to the wave equation. Simulations of interferograms from a Michelson interferometer illuminated with light sources of varying coherence lengths were developed to predict output intensity measurements. Spectral interferograms of broadband sources were then measured in the frequency domain using a Czerny-Turner mount monochromator with a 2048-element complementary metal oxide semiconductor linear array as the detector. One dimensional axial OCT images were computed by Fourier transformation of the measured spectra. Two dimensional colour-scaled slice images were then compiled by concatenation of 29 and 15 axial scans obtained from a 14 mm and 3.5 mm slice length respectively. Measured spectral interferograms, computed interference fringe signals and depth reflectivity profiles were comparable to simulations. Axial resolution of the imaging system was  $14.05\ \mu\text{m}$  and  $9.69\ \mu\text{m}$  using the 635 nm and 850 nm source respectively. Surface profile images of a double-step-function-surfaced sample showed a mean step height of  $161.00 \pm 1.00\ \mu\text{m}$  while line profiles of 0.5 mm-wide cracks revealed a mean crack depth of  $163.00 \pm 1.00\ \mu\text{m}$ , values which corresponded to thickness of microscope cover-slips used to fabricate the sample. Computed mean inclination angle of the sample relative to the incident beam was  $1.82^\circ$ , confirming sensitivity of the system to detect minute misalignments.